

GP 2851 \$  
#15/D  
5-17-00  
Robertson

XA-7889A Re

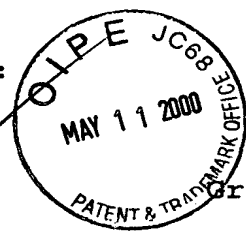
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Kenji NISHI

Appln. No.: 08/994,758



Group Art Unit: 2851

Filed: December 19, 1997

Examiner: A. Mathews

For: PROJECTION EXPOSURE APPARATUS

\* \* \*

AMENDMENT

Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

In response to the Office communication dated April 11, 2000, please amend the above-identified patent application as indicated below.

IN THE CLAIMS:

Please add the following new claims:

- DI
- 1        --169. An exposure apparatus in which a portion of a
  - 2        pattern of an original is projected onto a substrate and in
  - 3        which the original and the substrate are scanned
  - 4        synchronously such that the pattern of the original is
  - 5        transferred to the substrate, said apparatus comprising:

05/12/2000 SBUOMG 00000179 08994758

01 FC:102

156.00 OP

RECEIVED  
MAY 15 2000  
TECHNOLOGY CENTER 2800